

Supporting Information

Insights into the passivation effect of atomic layer deposited hafnium oxide for efficiency and stability enhancement in organic solar cells

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Additional Figures

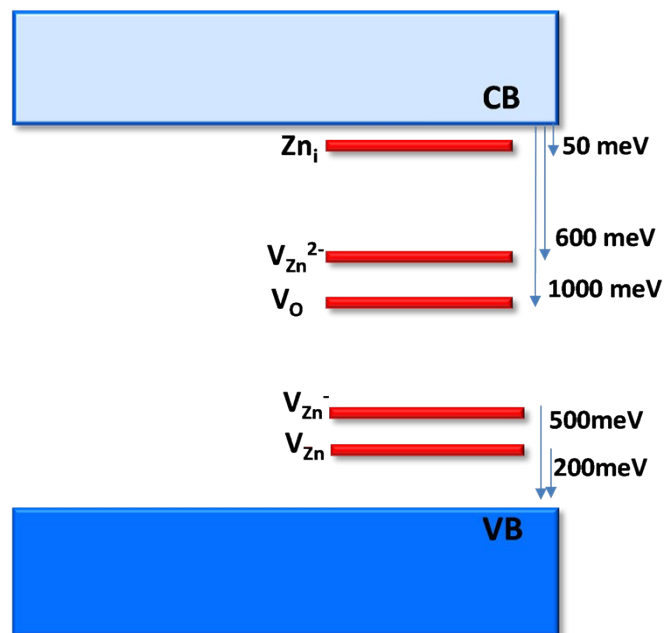


Figure S1 Schematic diagram depicting the various defect states in ZnO.¹⁻⁴

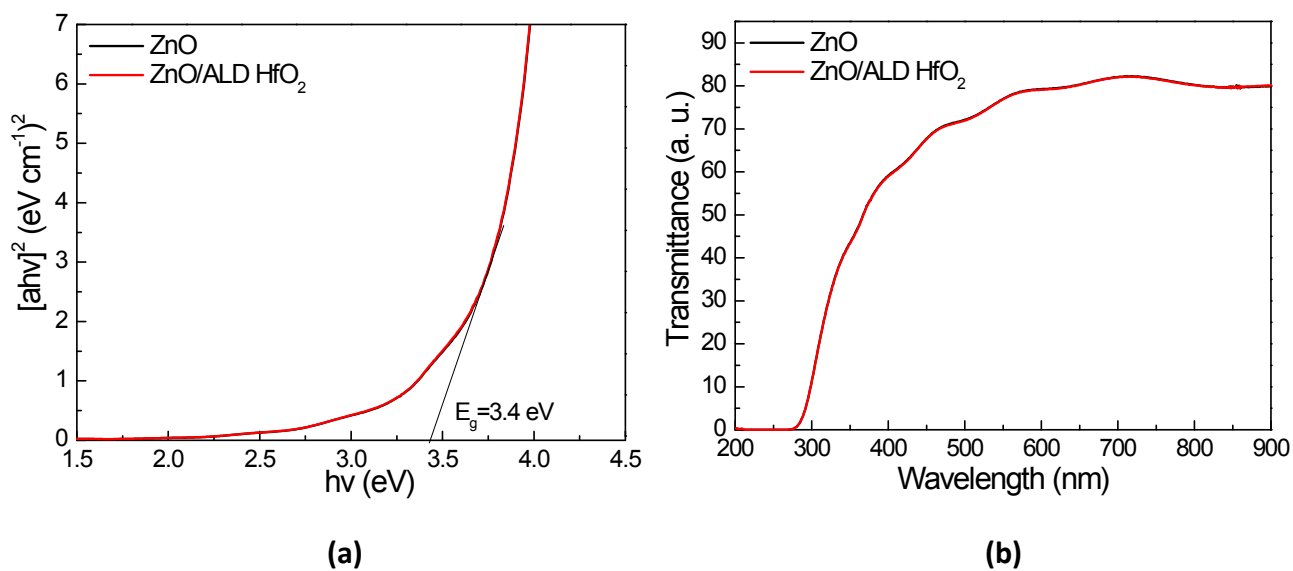


Figure S2 (a) Tauc plots as derived from UV-vis absorption measurements and (b) transmittance spectra of ~50 nm either as-deposited or passivated with 6 cycles of ALD HfO₂ ZnO films on glass/FTO substrates.

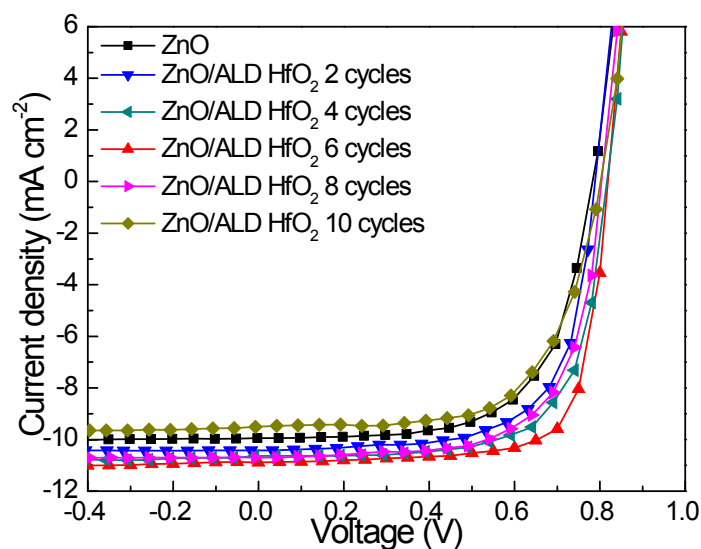


Figure S3 J-V characteristics under 1.5 AM illumination of P3HT:IC₆₀BA-based devices containing different cycles of ALD HfO₂ passivation interlayers.

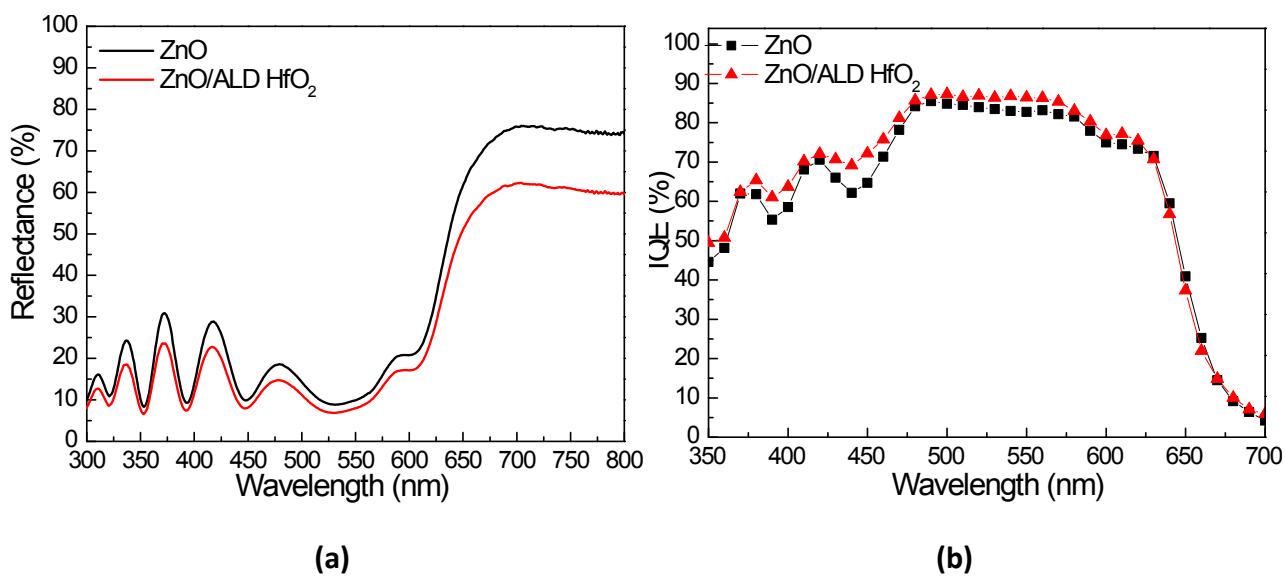


Figure S4 (a) Reflectance spectra and (b) IQE measurements of organic solar cells without and with ALD HfO₂.

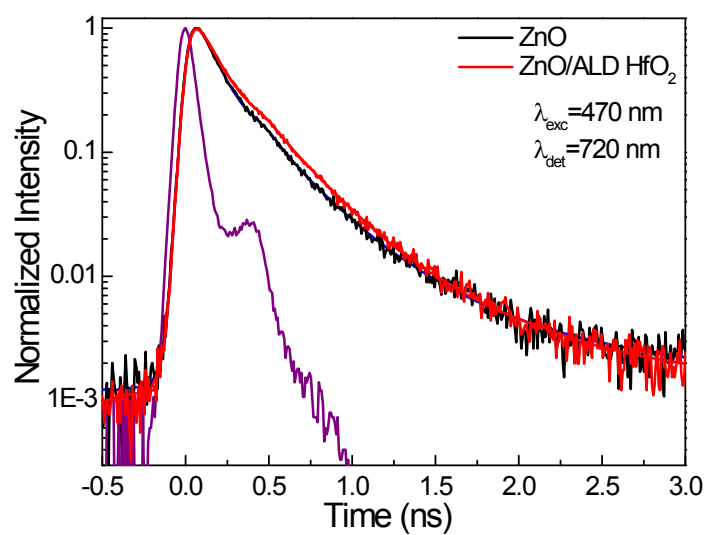


Figure S5 Transient PL dynamics of P3HT on ZnO and ZnO/ALD HfO₂ layers detected at 720 nm.

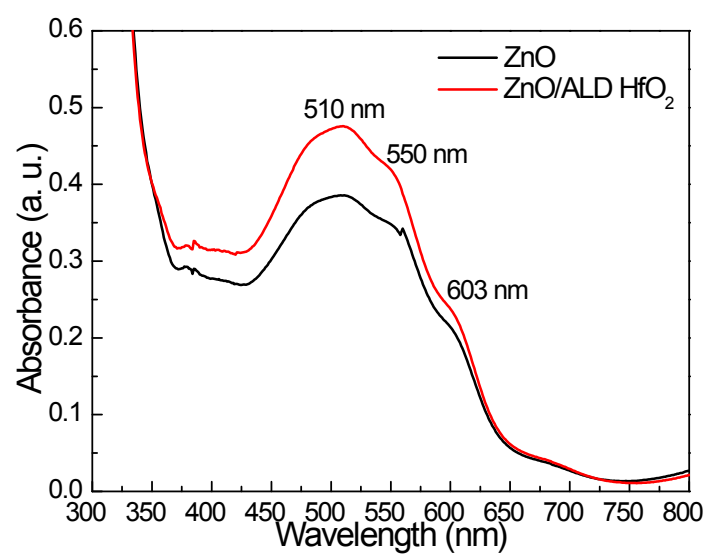


Figure S6 UV-vis absorption spectra of P3HT:IC₆₀BA blends on ZnO without and with ALD HfO₂.

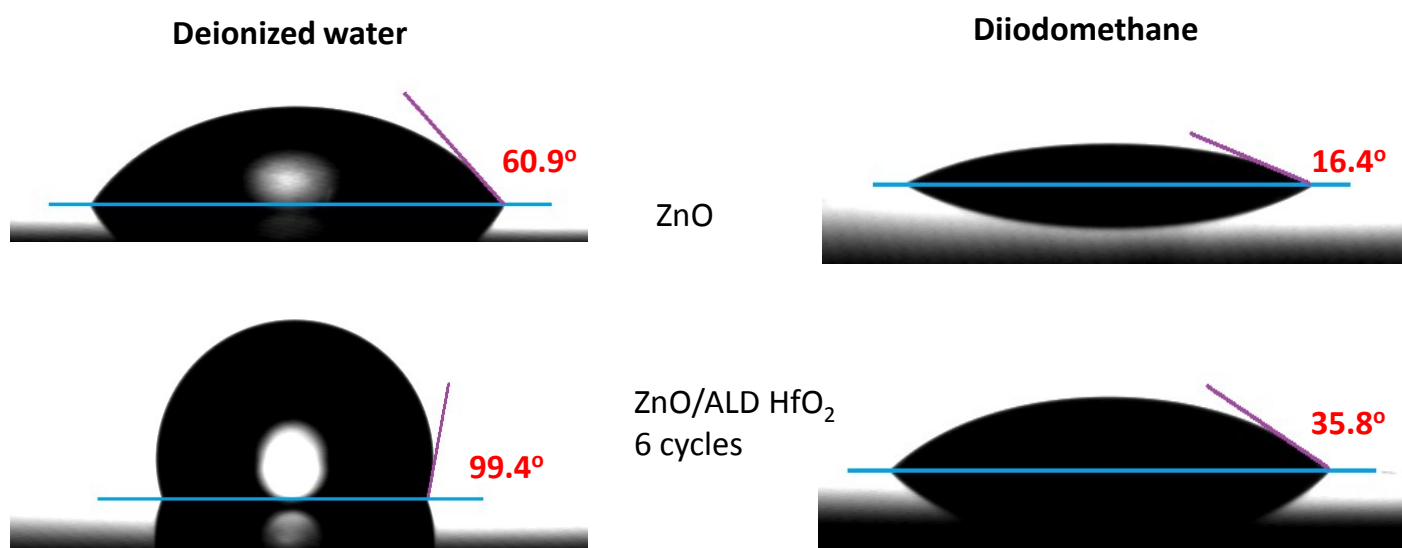


Figure S7 Contact angle measurements of deionized water and diiodomethane drops on ZnO without and with ALD HfO₂.

Additional Tables

Table S1 PL fitting parameters, obtained for P3HT 20 nm thick films (excitation wavelength: 470 nm) deposited on ZnO substrates without and with ALD HfO₂.

Substrate	λ_{det} (nm)	A_1	τ_1 (ns)	A_2	τ_2 (ns)	A_3	τ_3 (ns)	$\langle\tau\rangle$ (ns)
ZnO	650	0.81	0.09	0.18	0.31	0.01	1.41	0.14
ZnO	720	0.81	0.09	0.18	0.31	0.01	1.11	0.14
ZnO/ALD HfO ₂	650	0.68	0.11	0.31	0.34	0.01	1.20	0.19
ZnO/ALD HfO ₂	720	0.71	0.09	0.28	0.29	0.01	1.10	0.16

Table S2 Surface energy as derived from contact angle measurements of ZnO substrates without and with ALD HfO₂

Substrate	θ_w (°)	θ_i (°)	γ_{sp} (mJ m ⁻²)	γ_{sd} (mJ m ⁻²)	γ (mJ m ⁻²)
ZnO	60.9	16.4	10.87	42.83	53.70
ZnO/ALD HfO ₂	99.4	35.8	0.0002	42.85	42.85

Additional References

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